WHAT IS CLAIMED IS:

1. An actuator comprising:

a silicon structure, integrally formed from single-crystal silicon, having a pair of arms and a connecting part for connecting the arms to each other; and

respective piezoelectric devices attached to the arms.

2. An actuator according to claim 1, wherein each piezoelectric device has a form extending in one direction;

each piezoelectric device being attached to an outer side face of the respective arm such that a longitudinal direction of the piezoelectric device extends along a longitudinal direction of the arm.

3. An actuator according to claim 1, wherein the piezoelectric device is a laminated piezoelectric device.

4. An actuator according to claim 1, wherein the silicon structure is doped with an impurity so as to yield a lower resistance.

5. A method of making an actuator, the method comprising the steps of:

etching one surface of a single-crystal silicon substrate so as to form a plurality of plate-like projections arranged in parallel on the single-crystal silicon substrate;

cutting the single-crystal silicon substrate into a plurality of blocks each having a pair of plate-like

projections;

attaching an elongated piezoelectric device body to an outer side face of each of a pair of plate-like projections in each block; and

cutting the block having the elongated piezoelectric devices attached thereto into a plurality of actuators each comprising a silicon structure integrally formed with a pair of arms and a connecting part for connecting the arms to each other, and respective piezoelectric devices attached to the arms.